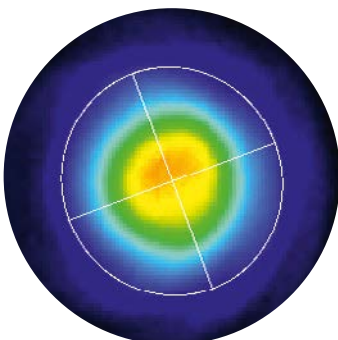


LBM2.0

Beam profiler for quick and easy
beam profiling



» The LBM2.0 is the latest Metrolux beam profiler for the simple measurement of all the most important beam parameters with the high precision you have come to expect from Metrolux. «



- A high-resolution Sony Pregius CMOS sensor with > 2 Mio. pixels and a pixel size of approx. 6 μm is used. The sensor's low noise and high linearity ensure highest accuracy in the evaluation of all beam parameters.
- The Beam Profiler is optimized for all common VIS/NIR- wavelengths and is immediately ready for use. Its small size allows the use in many laser systems, in which beam profilers are not employed yet, e.g. behind deflection mirrors for system adjustment, to control the position and size of laser beams or for continuous control of beam parameters during production.
- The analysis software, newly developed and optimized for measurement tasks in production, can be operated intuitively. The integration of measurement technology into automatic production processes can be realized easily. Software functions such as automatic exposure time, automatic ROI adjustment, real-time evaluation and an image display with a very high image refresh rate facilitate the adjustment of a laser beam in the shortest possible time.
- Comprehensive accessories (ND filters, near-field lenses) also enable the measurement of very small laser spots and of high power laser beams.

LBM2.0

Technical specifications

Sensor type

Sony Pregius CMOS 1/1.2

Resolution

1936 x 1216 pixels (WUXGA)

Pixel size

5,86 μm x 5,86 μm

Light-sensitive area

11.35 mm x 7.13 mm

Digital output

12 Bit

Maximum frame rate

40 fps

Camera control standard

GenICam SFNC V.1.2.1.1

Wavelength

400–1100 nm

Dimensions and interfaces

Lens Mount

C-Mount

Digital Interface

GigE Vision V 1.2

Synchronization

external trigger (5 V TTL) or free run

Dimensions (L x H x W)

60.5 mm x 29 mm x 29 mm

Weight

0.08 kg

Power supply

PoE or 12 to 24 VDC

Conformity

CE, RoHS, REACH, WEEE, FCC, ICES

Applications: Beam profiling

Beam size

55 μm to 6.5 mm

w/o additional optics

